SHEET <u>1</u> OF <u>7</u>

NAME CLASS SUBCLASS		ORMATION CITATIO APPLIC	N IN AN	SURE	5917/FET/FE		SERIAL NO. 09/998,372			
SAMINERS November 30, 2001 3723	6 IP	C 1714	1449)							
EXAMINER'S INITIALS PATENT NO. DATE NAME CLASS SUBCLASS FILING D 08/20/86 4,796,194 01/03/89 Atherton 08/20/86 5,089,970 02/18/92 Lee et al. 03/30/96 5,220,517 06/15/93 Sierk et al. 08/31/96 5,236,868 08/17/93 Nulman 04/20/96 5,260,868 11/09/93 Gupta et al. 70/0 5,309,221 05/03/94 Fischer et al. 01/13/93 5,329,463 07/12/94 Sierk et al. 01/13/93 5,367,624 11/22/94 Cooper	TRAN	SA S			November 30, 2001 3723					
NAME CLASS SUBCLASS	BIRAL	JEMPS 3	T	J.S. PATENT I	OCUMENTS		e e e e e e e e e e e e e e e e e e e			
5,089,970 02/18/92 Lee et al. 10/05/89 5,108,570 04/28/92 Wang 03/30/90 5,220,517 06/15/93 Sierk et al. 08/31/90 5,236,868 08/17/93 Nulman 04/20/90 5,260,868 11/09/93 Gupta et al. 10/15/91 5,295,242 03/15/94 Mashruwala et al. 11/02/90 5,309,221 05/03/94 Fischer et al. 12/31/91 5,329,463 07/12/94 Sierk et al. 01/13/93 5,367,624 11/22/94 Cooper		PATENT NO.	DATE		NAME	CLASS	SUBCLASS	FILING DATE		
5,108,570 04/28/92 Wang 03/30/90 5,220,517 06/15/93 Sierk et al. 08/31/90 5,236,868 08/17/93 Nulman 04/20/90 5,260,868 11/09/93 Gupta et al. 10/15/91 5,295,242 03/15/94 Mashruwala et al. 11/02/90 5,309,221 05/03/94 Fischer et al. 12/31/91 5,329,463 07/12/94 Sierk et al. 11/22/94 Cooper 06/11/93	66	4,796,194	01/03/89	Atherton				08/20/86		
5,220,517 06/15/93 Sierk et al. 08/31/90 5,236,868 08/17/93 Nulman 04/20/90 5,260,868 11/09/93 Gupta et al. 10/15/91 5,295,242 03/15/94 Mashruwala et al. 11/02/90 5,309,221 05/03/94 Fischer et al. 12/31/91 5,329,463 07/12/94 Sierk et al. 01/13/93 5,367,624 11/22/94 Cooper 06/11/93		5,089,970	02/18/92	Lee et al.			-	10/05/89		
5,236,868 08/17/93 Nulman 04/20/90 5,260,868 11/09/93 Gupta et al. 10/15/91 5,295,242 03/15/94 Mashruwala et al. 11/02/90 5,309,221 05/03/94 Fischer et al. 12/31/91 5,329,463 07/12/94 Sierk et al. 98,300 06/11/93		5,108,570	04/28/92	Wang				03/30/90		
5,309,221 05/03/94 Fischer et al. 12/31/91 5,329,463 07/12/94 Sierk et al. 12/31/91 5,367,624 11/22/94 Cooper 06/11/93		5,220,517	06/15/93	Sierk et al.	AR.		_	08/31/90		
5,309,221 05/03/94 Fischer et al. 12/31/91 5,329,463 07/12/94 Sierk et al. 12/31/91 5,367,624 11/22/94 Cooper 06/11/93		5,236,868	08/17/93	Nulman	**(冰, -		04/20/90		
5,309,221 05/03/94 Fischer et al. 12/31/91 5,329,463 07/12/94 Sierk et al. 11/22/94 Cooper 06/11/93		5,260,868	11/09/93	Gupta et al.	AUG.	1VE		10/15/91		
5,309,221 05/03/94 Fischer et al. 12/31/95 5,329,463 07/12/94 Sierk et al. 01/13/93 5,367,624 11/22/94 Cooper 06/11/93		5,295,242	03/15/94	Mashruwala e	et al. CHIVO	1 200		11/02/90		
5,329,463 07/12/94 Sierk et al. 01/13/93 5,367,624 11/22/94 Cooper 06/11/93		5,309,221	05/03/94	Fischer et al.	COGYCA	_ 5///-		12/31/91		
5,367,624 11/22/94 Cooper 06/11/93		5,329,463	07/12/94	Sierk et al.		1/290-		01/13/93		
1 000 000 000 m		5,367,624	11/22/94	Cooper		73700-		06/11/93		
5,398,336 03/14/95 Tantry et al. \(\frac{1}{2} \) \(\frac{1}{2} \) \(\frac{1}{2} \)		5,398,336	03/14/95	Tantry et al.				06/16/93		
5,402,367 03/28/95 Sullivan et al. 07/19/93		5,402,367	03/28/95	Sullivan et al.		_		07/19/93		
V 5,408,405 04/18/95 Mozumder et al 09/20/93	V	5,408,405	04/18/95	Mozumder et	al.			09/20/93		
BR 5,410,473 04/25/95 Kaneko et al. 12/16/92	BR	5,410,473	04/25/95	Kaneko et al.		-		12/16/92		
FOREIGN PATENT DOCUMENTS	<u> </u>	1	FOR	REIGN PATEN	T DOCUMENTS		7			
EM WILLER O	DITT II.ID IDITO							Translation		
INITIALS PATENT NO. DATE COUNTRY CLASS SUBCLASS Yes	INITIALS	PATENT NO.	DATE	(COUNTRY	CLASS	SUBCLASS	Yes No		
(3) 01-283934 11/15/89 Japan X	BB	01-283934	11/15/89	Japan				X		
	KA	2,050,247	08/29/91	Canada				X		
5,410,473 04/25/95 Kaneko et al. FOREIGN PATENT DOCUMENTS EXAMINER'S INITIALS PATENT NO. DATE COUNTRY CLASS SUBCLASS	EXAMINER'S	5,410,473 PATENT NO.	04/25/95 FOI DATE	Kaneko et al. REIGN PATEN	T DOCUMENTS	CLASS	SUBCLASS	760000		
	KA	2,050,247	08/29/91	Canada		_		X		

SHEET 2 OF 7

INF	ORMATION CITATIO APPLIC	N IN AN	SURE	ATTY. DOCKET NO. 5917/FET/FET/DV		SERIAL NO. 09/998,372		
SIPE	(PTO-	1449)		APPLICANT Young Joseph PAIK				
JUL 3 1 20			LECKED AUDONION	FILING DATE November 30,	, 2001	GROUP 3723		
G PRADENA	"		U.S. PATENT	DOCUMENTS	1		Leunz	DATE
EXAMINER'S INITIALS	PATENT NO.	DATE		NAME	CLASS	SUBCLASS	FILING	DATE
ŊΛ	5,490,097	02/06/96	Swenson et a	al.			08/06	/93
1	5,495,417	02/27/96	Fuduka et al		A=		03/16	/93
	5,497,316	03/05/96	Sierk et al.			04		/95
	5,503,707	04/02/96	Maung et al.	ÉC.	900-		09/22	/93
	5,508,947	04/16/96	Sierk et al.	EC _M , VC) 5		05/13	/94
	5,629,216	05/13/97	Wijaranakul	a et al.	V. C. N.Z.		02/27	/96
	5,657,254	08/12/97	Sierk et al.		100		04/15	/96
		08/26/97	Mozumder e	t al.	1 3		06/07	/95
	5,694,325	12/02/97	Fukuda et al	· · · · · · · · · · · · · · · · · · ·		30	11/22/95 09/13/96	
	5,698,989	12/16/97	Nulman					
	5,719,495	02/17/98	Moslehi				06/05	/96
	5,740,429	04/14/98	Wang et al.		+ =		07/07	/95
	5,751,582	05/12/98	Saxena et al.			<u></u>	09/24/96	
	5,754,297	05/19/98	Nulman				04/14	
00	5,764,543	06/09/98	Kennedy				06/16/95	
(XX				NT DOCUMENTS			00,10	
EXAMINER'S		T		· · · · · · · · · · · · · · · · · · ·			Tran	slation
INITIALS	PATENT NO.	DATE		COUNTRY	CLASS	SUBCLASS	Yes	No
ØQ.	2,165,847	08/29/91	Canada				X	
BB	2,194,855	08/29/91	Canada		-		X	T
S. Fig.	OTH	ER ART (Incl	uding Author,	Title, Date, Pertinen	t Pages, Et	c.)		
68	California: Acad	lemic Press, Ir	nc.	itegrated Circuit Man				
BR	-	Managing Equ		sh Shah. 1991. CEPT- lity and Availability ir	•		•	-
EXAMINER	Sen			DATE CONSIDERE	ED 32/20/	04		

INI	FORMATION CITATIO APPLIC	N IN AN	SURE	ATTY. DOCKET NO. SERIAL N 5917/FET/FET/DV 09/998,3)			
(3 1	10114	1449)		APPLICANT Young Joseph PAIK						
V.	1 2002			FILING DATE November 30, 2001 GROUP 3723						
I I I	ADEMASS		U.S. PATENT I	DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE		NAME	CLASS	SUBCLASS	FILING	DATE		
BO	5,808,303	09/15/98	Schlagheck et	al.	-		01/29/	97		
	5,838,595	11/17/98	Sullivan et al.				11/25/	96		
	5,883,437	03/16/99	Maruyama et	al.			12/28/	95		
V	5,910,011	06/08/99	Cruse				05/12/9	97		
KR	6,054,379	04/25/00	Yau et al.				02/11/9	98		
		FO	REIGN PATEN	NT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	C	OUNTRY	CLASS	SUBCLASS	Tran: Yes	slation No		
KB	05-151231	06/18/93	Japan		-	<u> </u>		X		
- CA	05-216896	08/27/93	Japan					X		
	05-266029	10/15/93	Japan					X		
	06-110894	04/22/94	Japan					X		
	06-176994	06/24/94	Japan				-	X		
	06-252236	09/09/94	Japan					X		
	06-260380	09/16/94	Japan					X		
	08-149583	06/07/96	Japan				X			
	09-34535	02/07/97	Japan				Х			
	EP 0877308 A2	11/11/98	Europe		_	<u> </u>	X			
V	11-67853	03/09/99	Japan				X			
RA	1072967A3	11/21/01	Europe		_		X			
	ОТН	ER ART (Inc	luding Author,	Title, Date, Pertin	ent Pages, E	tc.)	· · · · · · · · · · · · · · · · · · ·			
<u> </u>	Run-to-Run Contr Michigan: University Moyne, James, Ro Run-to-Run Contr Semiconductor Ma	oller for Plasm sity of Michigoland Telfeyan oller and Its A anufacturing (na Etching." Journan Display Techron, Arnon Hurwitz, pplication to Checonference and V	d Telfeyan. 1995. rnal of Vacuum Science Manufacturing, and John Taylor. emical-Mechanical Vorkshop Ann Arb	ence and Technical Center. August 1995. Planarization or, Michigan	"A Process-In." SEMI/IEEE	Arbor, ndepender Advance	ent red		
EXAMINER	00	bre			ED/20/0	4				

SHEET 4 OF 7

INI	CITAT	ON DIS TION IN LICATIO			ATTY. DOCKET NO. 5917/FET/FET/DV SERIAL NO. 09/998,372 AUG APPLICANT Young Joseph PAIK				
OIP	(PT	O-1449))	X	TECHNO - 1 200				
JII. 3 1	2002	.0 1112	,	APPLICANT Young Joseph PAIK FILING DATE GROUP AUG 12002 ZO02 APPLICANT GROUP					
13	at 3		*		FILING DATE November 30, 2001	GROUP 3723	73700		
MADE	MAN		U.S. PAT	ENT	DOCUMENTS				
EXAMINER'S INITIALS	PATENT FILING APPLICATION DATE NAME TITLE NO.						CLASS	SUB- CLASS	
Ba	09/363,966	07/29/99	Arackaparambil et al.	Con	nputer Integrated Manufacturing	g Techniques			
1	09/469,227	12/22/99	Somekh et al.	•	ti-Tool Control System, Method		1		
	09/619,044	07/19/00	Yuan		tem and Method of Exporting or ect Data in a Manufacturing Exe tem				
1	09/637,620	08/11/00	Chi et al.	Gen)			
BB.	09/656,031	09/06/00	Chi et al.	Mai	patching Component for Associate nufacturing Facility Service Require vice Providers		ſ		
			FOREIGN P	ATE	NT DOCUMENTS				
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY		CLASS	SUB- CLASS	Translation Yes No		
	Representation of the company of	kernete juli iki kutu yeso			, Title, Date, Pertinent Pages,	Secretary of Street Service Annual Control			
SS	Transform In	frared Spec		Real	5. "Epi-Film Thickness Measur I-Time in Situ Process Monitorio Vol. 8, No. 3.				
88	Moyne, Arno	n Hurwitz, chanical Pl	and John Taylor. anarization Proces	Octo	dhry, James Pugmire, Scott She ber 1995. "A Multi-Level Appr Minneapolis, Minnesota: 42 nd N	roach to the Co	ontrol of a	a	
ba	Nakagawa, S. Systematic an	Oh, and Dad Random	. Bartelink. Dece	mber nd W	Boning, J. Chung, K. Chang, G. 1995. "Using a Statistical Metr afer-level ILD Thickness Variat es Meeting.	ology Framev	vork to Id	entify	
EXAMINER	Sh	the			DATE CONSIDERED 02/20/04				

SHEET <u>5</u> OF <u>7</u>

	TION IN			5917/FET/FET/DV	037376,2	SERIAL NO. 09/998,372				
(PI	O-1449))								
E de				APPLICANT Young Joseph PAIK						
1 2002				FILING DATE November 30, 2001	GROUP 3723					
DEMARK		U.S. PA	TENT I	DOCUMENTS		X				
PATENT APPLICATION	FILING DATE	NAME		TITLE		CLASS	SUB- CLASS			
09/655,542	09/06/00	Yuan	Palette	es to Transform an Application						
09/725,908	11/30/00	Chi et al.				_				
09/800,980	03/08/01	Hawkins et al.								
09/811,667	03/20/01	Yuan et al.		-	_					
09/927,444	08/13/01	Ward et al.	Dynamic Control of Wafer Processing Paths in							
09/928,473	08/14/01	Koh	Tool S	Services Layer for Providing T	_	_				
		FOREIGN					1 1/			
PATENT NO.	DATE	COUNTRY		CLASS	SUB- CLASS	Translation Yes No				
							-			
	THER A	L RT (Including, A	Author,	Title, Date, Pertinent Pages,	Etc.)		17.1			
February 199	6. "On-Lin	e Integrated Me	trology f	For CMP Processing." Santa C						
Smith, Taber, CMP Pad We	Duane Bo	ning, James Moy	yne, Arno	on Hurwitz, and John Curry. J						
Boning Duar	ne, William I John Tayl	Moyne, Taber Solor. October 199	Smith, Ja 96. "Run 97-314.	mes Moyne, Roland Telfeyan, by Run Control of Chemical-	Arnon Hurw Mechanical P	itz, Scott olishing."	IEEE			
SEMI. [1986] Maintainabili	1996. "State (RAM)."	andard for Defin ' SEMI E10-96.	ition and	Measurement of Equipment I	Reliability, Av	ailability,	and			
Shi	Dre		I	DATE CONSIDERED 02/20/04	₽.					
itial if reference co not considered. Ir	nsidered, whe nclude copy of	ther or not citation i f this form with next	s in confor	mance with MPEP 609; draw line thr cation to Applicant.	ough citation its	Roop C)			
	APPI (PT 1 2002 PATENT APPLICATION NO. 09/655,542 09/800,980 09/800,980 09/811,667 09/927,444 09/928,473 PATENT NO. Dishon, G., M. February 199 Speciality Co. Smith, Taber, CMP Pad We Conference. Boning Duar	APPLICATION (PTO-1449) 1 2002 PATENT APPLICATION DATE NO. 09/655,542 09/06/00 09/800,980 09/800,980 09/811,667 03/20/01 09/927,444 08/13/01 09/928,473 08/14/01 PATENT NO. DATE OTHER APPLICATION DATE OTHER A	PATENT APPLICATION NO. 09/655,542 09/06/00 Vuan 09/725,908 11/30/00 Chi et al. 09/800,980 03/08/01 Hawkins et al. 09/811,667 03/20/01 Vuan et al. 09/927,444 08/13/01 Ward et al. 09/928,473 08/14/01 Koh FOREIGN PATENT NO. DATE COUNTRY OTHER ART (Including, February 1996. "On-Line Integrated Me Speciality Conferences, 1st International Smith, Taber, Duane Boning, James Mo CMP Pad Wear Using Run by Run Feed Conference. Boning Duane William Moyne Taber States of the s	APPLICATION (PTO-1449) U.S. PATENT I PATENT APPLICATION DATE NAME NO. 09/655,542 09/06/00 Yuan System Palette Interfa 09/725,908 11/30/00 Chi et al. Dynam Messa 09/800,980 03/08/01 Hawkins et al. Dynam Messa 09/801,667 03/20/01 Yuan et al. Fault Softwa 09/927,444 08/13/01 Ward et al. Dynam Semic 09/928,473 08/14/01 Koh Tool S Functi FOREIGN PATEN PATENT NO. DATE COUNTRY Dishon, G., M. Finarov, R. Kipper, J.W. Curry, T February 1996. "On-Line Integrated Metrology of Speciality Conferences, 1st International CMP Plasmith, Taber, Duane Boning, James Moyne, Arnother CMP Pad Wear Using Run by Run Feedback Conference. Boning Duane William Moyne Taber Smith, Iaber, I	APPLICATION APPLICANT Young Joseph PAIK FILING DATE November 30, 2001 U.S. PATENT DOCUMENTS PATENT APPLICATION DATE NO. 09/655,542 09/06/00 Vuan System, Method and Medium for De Palettes to Transform an Application Interface for a Service 09/725,908 11/30/00 Chi et al. Dynamic Subject Information Gener Message Services of Distributed Obj 09/800,980 03/08/01 Hawkins et al. Dynamic and Extensible Task Guide 09/811,667 03/20/01 Yuan et al. Fault Tolerant and Automated Comp Software Workflow 09/927,444 08/13/01 Ward et al. Dynamic Control of Wafer Processir Semiconductor Manufacturing Proce 09/928,473 08/14/01 Koh Tool Services Layer for Providing T Functions in Conjunction with Tool FOREIGN PATENT DOCUMENTS PATENT NO. DATE COUNTRY CLASS Dishon, G., M. Finarov, R. Kipper, J. W. Curry, T. Schraub, D. Trojan, 4 th Stam February 1996. "On-Line Integrated Metrology for CMP Processing." Santa C Speciality Conferences, 1 th International CMP Planarization Conference. Smith, Taber, Duane Boning, James Moyne, Arnon Hurwitz, and John Curry. J CMP Pad Wear Using Run by Run Feedback Control." Santa Clara, California Conference. Boning, Duane, William Moyne, Taber Smith, James Moyne, Roland Telfevan.	APPLICATION (PTO-1449) APPLICANT Young Joseph PAIK FILING DATE November 30, 2001 PATENT APPLICATION NO. 123 U.S. PATENT DOCUMENTS PATENT NO. 124 PATENT APPLICATION NO. 125 PATENT APPLICATION DATE NAME TITLE NAME System, Method and Medium for Defining Palettes to Transform an Application Program Interface for a Service 126 127 128 129 129 129 129 129 120 120 120	APPLICATION APPLICANT Young Joseph PAIK FILING DATE November 30, 2001 APPLICANT Young Joseph PAIK FILING DATE November 30, 2001 APPLICANT FILING DATE November 30, 2001 APPLICANT FILING DATE November 30, 2001 APPLICANT November 30, 2001 APPLICANT FILING DATE November 30, 2001 APPLICANT FILING PATENT APPLICATION NO. O9/655,542 O9/06/00 Yuan System, Method and Medium for Defining Palettes to Transform an Application Program Interface for a Service O9/725,908 11/30/00 Chi et al. Dynamic Subject Information Generation in Message Services of Distributed Object Systems O9/800,980 O3/08/01 Hawkins et al. Dynamic and Extensible Task Guide O9/811,667 O3/20/01 Yuan et al. Fault Tolerant and Automated Computer Software Workflow O9/927,444 O8/13/01 Ward et al. Dynamic Control of Wafer Processing Paths in Semiconductor Manufacturing Processes O9/928,473 O8/14/01 Koh Tool Services Layer for Providing Tool Service Functions in Conjunction with Tool Functions FOREIGN PATENT DOCUMENTS PATENT NO. DATE COUNTRY CLASS SUB- CLASS OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.) Dishon, G., M. Finarov, R. Kipper, J.W. Curry, T. Schraub, D. Trojan, 4th Stambaugh, Y. Li and J. Ber February 1996. "On-Line Integrated Metrology for CMP Processing." Santa Clara, California: VMIC Speciality Conferences, 1th International CMP Planarization Conference. Smith, Taber, Duane Boning, James Moyne, Arnon Hurwitz, and John Curry. June 1996. "Compensal CMP Pad Wear Using Run by Run Feedback Control." Santa Clara, California: VLSI Multilevel International CMP Pad Wear Using Run by Run Feedback Control." Santa Clara, California: VLSI Multilevel International CMP Planarization Conference.			

SHEET <u>6</u> OF <u>7</u>

	-			ATTY. DOCKET NO. SERIAL NO.							
INI		ON DIC	CLOCUDE	5917/FET/FET/DV							
IIN	FORMATION				1.	De					
	CITAT	ION IN	AN			UEC	7				
	APPL	ICATIO)N			4.	10/12				
		O-1449			AUG -						
GIPE	(1 1	U-1447	,	A DDI ICANE	I FC/M	<u> </u>	2000				
\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\	· 46.				APPLICANT Young Joseph PAIK FILING DATE RECEIVE AUG - 1 2002 TECHNOLOGY CENTER AG:						
V	4			Young Joseph PAIK							
JUL 3 1 2	ببر 2002			FILING DATE GROUP							
70 70	<u></u>			November 30, 2001	3723						
CAL	ARTS	* ** ** **	U.S. PATENT	DOCUMENTS	J (** 144 -)						
TA TRADE			- CISTATENT	DOCOMENTS	× 1						
EXAMINER'S INITIALS	PATENT APPLICATION NO.	FILING DATE	NAME	TITLE		CLASS	SUB- CLASS				
BB	09/928,474	08/14/01	Krishnamurthy et al.	Experiment Management Syste and Medium		•					
	09/943,383	08/31/01	Shanmugasundram	In Situ Sensor Based Control of							
			et al.	Semiconductor Processing Pro		1					
X	09/943,955	08/31/01	Shanmugasundram	Feedback Control of a Chemic		-					
BR	et al. Polishing Device Providing Manipulation Removal Rate Profiles										
			FORFIGN PATE	ENT DOCUMENTS	+ 15		*				
EXAMINER'S	T		TORDIGITIALI	I DOCUMENTO		, ×	Y 18 1				
INITIALS	PATENT NO. DATE	COUNTRY	CLASS		SUB-	Translation					
						CLASS					
							Yes No				
	0	THER AR	T (Including Author	, Title, Date, Pertinent Pages,	Etc.)	× ×					
	Van Zant, Pete	er. 1997. M	icrochip Fabrication:	A Practical Guide to Semicond	luctor Processi	ng. Thir	d Edition.				
l BB.			New York: McGraw-				,				
1				February 11-12, 1998. "Run-to-	Run Control in	n Microe	lectronics				
	Manufacturing	g." Advanc	ed Micro Devises, TV	VMCC.							
				Campbell, Carlos Pfeiffer, Chri							
1				ntrol in Microelectronics Manuf	facturing: Prac	tices, Ch	allenges,				
			natica, Vol. 36, pp. 15								
			•	Fully Automated Chemical-Mo		arızatıon	Process."				
				onnection (V-MIC) Conference		1.:44					
	1			Specification for CIM Framewood SEMI Draft Doc. 2817.	rk Domain Arc	nueciure	•				
				Component: QMC TM and QMC	LinkTM Overv	iew Mo	untain				
	View, Californ	_	- , ,	Component. QITC " unu QITC	Link Overv	LOTE. IVIC	anan				
				Khan, Rock Nadeau, Paul Smi	th. John Colt. J	onathan	Chapple-				
				Iultizone Uniformity Control of							
				hington: SEMETECH Symposi		<u>.</u>					
Y				California: Consilium, Inc.							
ØB			or Solakhain, Anthony s." Ann Arbor, Mich	Ricci, Tier Gu, and James Moyigan.	ne. 1998. "R	un-to-Ru	ın Control				
	() ^	()									
EXAMINER	' X_U	Y		DATE CONSIDERED							
	الماكل	The		ozlegay							
L				3441							

SHEET 7 OF 7 ATTY. DOCKET NO. SERIAL NO. 09/998,372 5917/FET/FET/DV INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449) APPLICANT Young Joseph PAIK FILING DATE GROUP November 30, 2001 3723 U.S. PATENT DOCUMENTS EXAMINE **FILING** CLASS SUB-INITIALS APPLICATION NAME DATE NO. **CLASS** FOREIGN PATENT DOCUMENTS 100 EXAMINER'S INITIALS PATENT NO. DATE **COUNTRY CLASS** SUB-Translation **CLASS** Yes No OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.) Consilium. January 1999. "FAB300TM: Consilium's Next Generation MES Solution of Software and Services 50 which Control and Automate Real-Time FAB Operations." www.consilium.com/products/fab300_page.htm#FAB300 Introduction Consilium. July 1999. "Increasing Overall Equipment Effectiveness (OEE) in Fab Manufacturing by Implementing Consilium's Next-Generation Manufacturing Execution System - MES II." Semiconductor Fabtech Edition 10. Consilium Corporate Brochure. October 1999. www.consilium.com Moyne, James. October 1999. "Advancements in CMP Process Automation and Control." Hawaii: (Invited paper and presentation to) Third International Symposium on Chemical Mechanical Polishing in IC Device Manufacturing: 196th Meeting of the Electrochemical Society. Consilium. November 1999. FAB300TM Update. SEMI. 2000. "Provisional Specification for CIM Framework Scheduling Component." San Jose, California. SEMI E105-1000. Lee, Brian, Duane S, Boning, Winthrop Baylies, Noel Poduje, Pat Hester, Yong Xia, John Valley, Chris Koliopoulus, Dale Hetherington, HongJiang Sun, and Michael Lacy. April 2001. "Wafer Nanotopography Effects on CMP: Experimental Validation of Modeling Methods." San Francisco, California: Materials Research Society Spring Meeting. NovaScan 2020. February 2002. "Superior Integrated Process Control for Emerging CMP High-End Applications."

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

DATE CONSIDERED

EXAMINER